Appl. No. 10/810,151 Amdt. Dated May 4, 2006

Reply to Office Action of March 10, 2006

Amendments to the Claims:

This listing of claims will replace all prior versions and listings of claims in

the application:

Listing of Claims:

Claim 1 (previously presented): A method for making a carbon

nanotube-based field emission display, comprising steps of:

providing an insulative layer having a first surface;

depositing a layer of catalyst on the first surface of the insulative layer;

forming a spacer having a plurality of openings therein such that

patterned areas of the layer of catalyst are exposed in the openings;

forming arrays of carbon nanotubes extending from the layer of catalyst

in the patterned areas;

forming cathode electrodes on tops of the arrays of carbon nanotubes;

forming gate electrodes on a second, opposite surface of the insulative

layer offset from the patterned areas;

removing portions of the insulative layer corresponding to the arrays of

carbon nanotubes so as to expose the arrays of carbon nanotubes; and

attaching an anode electrode having a phosphor screen to the above

obtained structure.

Page 2 of 8

MAY-04-2006 16:57 7147384649 P.04

Appl. No. 10/810,151 Amdt. Dated May 4, 2006

Reply to Office Action of March 10, 2006

Claim 2 (original): The method as described in claim 1, wherein a

flatness of the first surface of the insulative layer is less than 1 micron.

Claim 3 (previously presented): The method as described in claim 1,

wherein a thickness of the insulative layer is in the range from 1 micron to

1000 microns.

Claim 4 (original): The method as described in claim 3, wherein the

thickness of the insulative layer is in the range from 10 microns to 200

microns.

Claim 5 (original): The method as described in claim 1, wherein a

thickness of the catalyst layer is in the range from 1 nanometer to 10

nanometers.

Claim 6 (previously presented): The method as described in claim 1,

wherein the spacer is made of heatproof glass, metal coated with insulative

material, silicon, silicon oxide, ceramic, or mica.

Claim 7 (previously presented): The method as described in claim 1,

wherein a height of the spacer is in the range from 1 micron to 1 mm.

Page 3 of 8

MAY-04-2006 16:57 7147384649 P.05

Appl. No. 10/810,151 Amdt. Dated May 4, 2006 Reply to Office Action of March 10, 2006

Claim 8 (currently amended): The method as described in claim [[8]] 7, wherein the height of the spacer is in the range from 10 microns to 500 microns.

Claim 9 (original): The method as described in claim 1, wherein a height of the arrays of carbon nanotubes is approximately equal to that of the spacer.

Claim 10 (original): The method as described in claim 1, wherein each cathode electrode further includes a negative feedback layer.

Claim 11 (previously presented): A method for making a carbon nanotube-based field emission display, comprising steps of:

providing an insulative layer having a first surface;

depositing a protective layer on the insulative layer;

depositing a layer of catalyst on the protective layer;

forming a spacer having a plurality of openings therein such that patterned areas of the layer of catalyst are exposed in the openings;

forming arrays of carbon nanotubes extending from the layer of catalyst in the patterned areas;

forming a cathode electrode on a top of each of the arrays of carbon nanotubes;

MAY-04-2006 16:58 7147384649 P.06

Appl. No. 10/810,151 Amdt. Dated May 4, 2006

Reply to Office Action of March 10, 2006

forming a base having an inner contour that mates with an outer contour

of the cathode electrodes and the spacer so as to couple the base to the

cathode electrodes and the spacer;

forming gate electrodes on a second, opposite surface of the insulative

layer offset from the patterned areas;

removing portions of the protective layer and the insulative layer

corresponding to the arrays of carbon nanotubes so as to expose the arrays of

carbon nanotubes; and

attaching an anode electrode having a phosphor screen to the above

obtained structure.

Claim 12 (previously presented): The method as described in claim 11,

wherein a flatness of the first surface of the insulative layer is less than 1

micron.

Claim 13 (original): The method as described in claim 11, wherein a

thickness of the insulative layer is in the range from 1 micron to 1000

microns.

Claim 14 (original): The method as described in claim 11, wherein a

thickness of the protective layer is in the range from 10 nanometers to 100

nanometers.

Page 5 of 8

Appl. No. 10/810,151 Andt. Dated May 4, 2006 Reply to Office Action of March 10, 2006

Claim 15 (original): The method as described in claim 11, wherein the insulative layer and the protective layer are removed by wet etching and dry etching respectively.

Claim 16 (original): The method as described in claim 11, wherein a thickness of the layer of catalyst is in the range from 1 nanometer to 10 nanometers.

Claim 17 (original): The method as described in claim 11, wherein the method further includes a step of cleaning the exposed surface of the arrays of carbon nanotubes after removing the portions of the protective layer and the insulative layer.

Claim 18 (previously presented): A method of making a carbon nanotube-based field emission display, comprising steps of:

providing a catalyst layer;

forming a barrier on the catalyst layer;

growing arrays of carbon nanotubes beside the barrier on the catalyst layer;

applying a cathode electrode upon the arrays of carbon nanotubes under a condition that the cathode electrode is supported by the barrier;

removing portions of the catalyst layer;

providing a gate electrode under the arrays of carbon nanotubes; and locating an anode electrode spatially away from the arrays of carbon nanotubes, opposite to the cathode electrode.